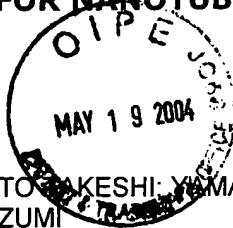


**MANUFACTURING METHOD FOR NANOTUBE PROBE**

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**Classification:**

- **international:** B82B3/00; C01B31/02; G01N13/12; G01N13/16

- **european:**

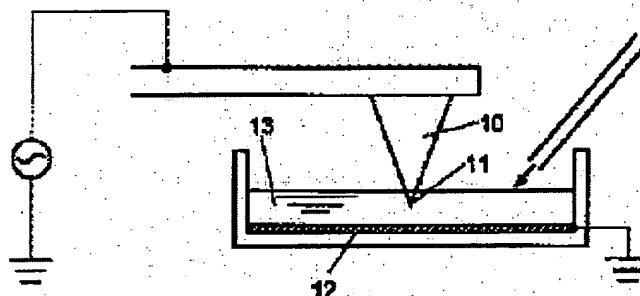
**Application number:** JP20010106641 20010405

**Priority number(s):**

**Abstract of JP2002301700**

**PROBLEM TO BE SOLVED:** To provide a method of easily manufacturing a nanotube probe in a short time.

**SOLUTION:** When the alternating current voltage is applied between a holder 10 having a sharp end 11 and an opposed electrode 12, electric lines of force connecting both the electrodes 10 and 12 is concentrated to the sharp end 11. In this condition, the liquid (migration liquid) 13 including nanotubes is interposed between the sharp end 11 of the holder 10 and the opposite electrode 12 so that the nanotubes are orientated along the electric lines of force in the longitudinal direction thereof. Multiple nanotubes are concentrated to the sharp end 11 of the holder 10, to which the electric power line is concentrated, and a part thereof is adhered to the sharp end 11 of the holder 10. The adhered nanotube 14 is fixed to the sharp end 11 of the holder 10 by the Van der Waals force.



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